



AFTER FINAL

21W
AF

In re the Application of:

Seung-un KIM, et al.

Art Unit: 1763

Serial No. 10/800,735

Examiner: S. MacArthur

Filed: March 16, 2004

Confirmation No. 1171

For: APPARATUS AND METHOD FOR SUPPLYING
CHEMICALS IN CHEMICAL MECHANICAL
POLISHING SYSTEMS

Attorney Docket No. 239/166 DIV

REQUEST FOR RECONSIDERATION UNDER 37 C.F.R. § 1.116
AND APPLICANT INITIATED INTERVIEW SUMMARY

Mail Stop AF
Commissioner for Patents
United States Patent and Trademark Office
P.O. Box 1450
Alexandria, Virginia 22313-1450

Sir:

INTRODUCTORY COMMENTS

In response to the Office action mailed March 28, 2005, the following remarks and amendments are respectfully submitted in connection with the above-identified application:

A Listing of the Claims begins on page 2 of this paper.

Remarks/Arguments begin on page 6 of this paper.